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Sheet **1** of **1**

Complete If Known

Application Number **10/086,652**
Filing Date **February 28, 2002**
First Named Inventor **Ashurst, William R.**
Group Art Unit **1762**
Examiner Name **To Be Assigned**
Attorney Docket Number **02307V-121600US**

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

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WA	AL	ASHURST, W. et al., "Dichlorodimethylsilane as an anti-stiction monolayer for MEMS: A comparison to the octadecyltrichlorosilane self assembled monolayer," Journal of Microelectromechanical Systems, 2001, pp. 41-49, Vol. 10(1).	
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